

|   | Type | L # | Hits | Search Text   | DBs             |
|---|------|-----|------|---|-----------------|
| 1 | BRS  | L1  | 497  | vacuum and<br>((substrate wafer)<br>adj handling) and<br>(mask reticle) | USPAT; US-PGPUB |
| 2 | BRS  | L2  | 177  | 1 and lithography   | USPAT; US-PGPUB |
| 3 | BRS  | L3  | 59   | 2 and arm   | USPAT; US-PGPUB |